

Background

- Pixels in imaging sensors do not have uniform response across the pixel area • Intra-pixel sensitivity is important for analysis requiring high photometric precision

Goals

- Fabricate a spot-projector capable of producing a spot much smaller than the size of a pixel
- Validate the spot-projector's capability
- Measure the intra-pixel response for a hybrid CMOS detector

Spot-Projector Fabrication





Figure 1: Top: Schematic diagram of optical components of the spot-projector with ray tracing (Red). Bottom: Setup of spot-projector system.

Spot-Projector Properties

- Able to produce a spot as small as 5.7 μm to as large as 1 mm
- Capability to move spot images in three independent axes
- Able to produce images over a broad wavelength range



Spot-Projector System for the Measurement of Intra-Pixel Response Young Sam Yu (RIT, Imaging Science PhD Student)

Expected Spot Size



Result



Spot Size Calculation

- Pinhole image size = 119 pixels x 9 μ m/pixel = 1.07 mm
- Expected image size = 1.0 mm

Summary

Future Work





• Diffraction limit = $1.22 \lambda f/D = 1.22 \lambda f/\# = 0.61 \lambda/N.A. = 2.78 \mu m$ Demagnification = 10X

 Spot Size = sqrt((Dia._{diffraction limit})² + (Demagnification of Image)²) Calculations use 632 nm wavelength light

Pinhole size	Expected Spot Size (w/o Diffraction)	Expected (w/Diff
10 mm	1 mm	11
10 µm	1 µm	5.7



Figure 2. Image of 10 mm pinhole with 10X demagnification. Left: Image of 10 mm pinhole on a CCD with 9 µm pixel pitch. Right: Plot of intensity vs. radial distance from the center of the spot. Red line is at the FWHM (59.5 pixel radius).

- FWHM diameter = 119 pixels
- Pixel pitch = $9 \mu m/pixel$

 Demonstrated that our spot-projector is successfully working (Fig. 2) Measured demagnification is within 10% of the calculated value

 Measure the point spread function of the spot-projector using the knife-edge technique and a 10 µm pinhole Measure the intra-pixel response of a hybrid CMOS image sensor